



**CARE**

Centre for Applied Research in Electronics

# Industry Lecture Series on Semiconductor Manufacturing

## LPCVD Techniques in Microfabrication: A Comprehensive Lecture Series

**Dr. Wayne H. Choe**  
**CEO, Tystar Corporation**

Dr. Choe received a Ph.D. from MIT in 1985 in Plasma Physics. He has published over 100 articles in reputable international journals and proceedings. He is an inventor of six patented concepts ranging from ultrahigh-efficiency solar cells to millimeter wave filters. Currently, he is the CEO of Tystar Corporation, California which was formed in 1988. Tystar is a service and solutions-oriented electronics and semiconductor equipment supplier specializing in diffusion, oxidation and LPCVD furnace systems as well as related equipment.



**Abstract:** This lecture series delves into Low-Pressure Chemical Vapor Deposition (LPCVD), exploring its critical role in advancing semiconductor manufacturing. It covers the impact of process parameters like pressure, temperature, and gas flow rates on film characteristics essential for applications such as gate dielectrics and passivation layers. The series offers a historical overview, insights into process optimization, and practical knowledge through case studies and discussions. Aimed at both seasoned professionals and aspiring technologists, these lectures provide valuable tools and insights to advance LPCVD technology.

**Date: 9 September 2024**  
**Time: 09:30 AM to 3:30 PM**  
**Venue: B-III,**  
**CARE Committee Room**

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**Last Date of Registration**  
**28/08/2024**

**Registered Participants Only Allowed to Attend The Event**